



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/530,689
Filing Date.....April 7, 2005
Inventor..... Ulrich Weber, et al.
Assignee Carl Zeiss SMT AG
Group Art Unit.....2873
Examiner..... Joseph P. Martinez
Attorney's Docket No. LO29-023
Title: Objective, in Particular a Projection Objective in Microlithography

To: Commissioner for Patents
P.O. Box 1450
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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

The attached Form PTO-1449 is submitted In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the references listed on the attached Form PTO-1449. Pursuant to Federal Register Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art references, if any, are attached. No admission is made regarding whether the submitted references are prior art.

Citation of this reference is respectfully requested.

Respectfully submitted,

Dated:

5-30-06

By:

D. Brent Kenady
Reg. No. 40,045

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Form PTO-1449

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PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
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10/530,689LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Ulrich Weber, et al.FILING DATE
April 7, 2005GROUP
2873

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,529,264	03/03	Ikeda	355	53	
	AB						
	AC						
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	AG						
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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
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	AM							
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.